

Image PATENT

1765

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Date: 12/23/03

Rebecca A. Bellas
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of:

Applicant: Phan, *et al.*

Examiner: Duy Vu Nguyen Deo

Serial No: 10/052,173

Art Unit: 1765

Filing Date: January 17, 2002

Title: IN-SITU CHEMICAL COMPOSITION MONITOR ON WAFER DURING PLASMA ETCHING FOR DEFECT CONTROL

**Mail Stop Non Fee Amendments
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450**

REPLY TO OFFICE ACTION DATED SEPTEMBER 25, 2003

Dear Sir:

Favorable reconsideration of the above-identified patent application is respectfully requested in view of the amendments and comments below.

Claims 5-8, 20, and 21 have been amended on pages 3 and 4.

Replacement sheets for all figures (1-6) are attached.